EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	0	diode near laser near4 source near4 (heating or heated or heat) near4 (semiconductor or substrate or wafer or chip) and depost\$4 near material and melt near pool and diode near laser near4 (energy or power) near source	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/11 10:50
L2	0	diode near laser near4 source near4 (heating or heated or heat) near4 (semiconductor or substrate or wafer or chip) and depost\$4 near material and melt near pool and diode near laser near4 (energy or power) near source and optical near signal	US-PGPUB; USPAT; USOOR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/11
L3	0	diode near laser near4 source near4 (heating or heated or heat) near4 (semiconductor or substrate or wafer or chip) and depost% near material and imelt near pool and diode near laser near4 (energy or power) near3 source and optical near signal	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/11

L4	0	diode near laser near4 source near4 (heating or heated or heat) same (semiconductor or substrate or wafer or chip) and depost\$6 near material and melt near pool and diode near laser near4 (energy or power) near3 source and optical near signal	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/11 10:53
L5	0	feeding near matrial same melt near pool same deposit\$ and monitoring near laser near interaction near zone and diode near laser with (power or energy) near3 source and optical near signal	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/11 10:55

EAST Search History (Interference)

Ref#	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L6	0	feeding near matrial same melt near pool same deposits and monitoring near laser near interaction near zone and diode near laser with (power or energy) near3 source and optical near sional	USPAT; UPAD	OR	ON	2010/03/11 10:55

3/11/2010 10:56:32 AM